



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

| In Re | Application of) | | |
|--------------------------|--|--|---------|
| Hiroki et al. | | I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313, 450 on (Date of Deposit) | |
| Serial No.: 09/776,472) | | | |
| Filed: February 2, 2001 | | | |
| For: | Thin Film Formation Apparatus And) Method Of Manufacturing Self-Light-) Emitting Device Using Thin Film) Formation Apparatus) | Shannon Wallace Name of applicant, assignature | 1 0/0 / |
| Art Unit: 1762) | | | |
| Exam | niner: M. Cleveland) | | |
| Comr | nissioner for Patents | | |
| P.O. 1 | Box 1450 | | |
| Alexa | andria VA 22313-1450 | | |

AMENDMENT G (AFTER FINAL)

Sir:

In response to the Final Rejection of May 31, 2005, an RCE being submitted herewith, please amend the above-identified application as follows: